

First name and name Author :: Function :: Paul Scherrer Institute



### TSMC 28nm overview

 From discussions at PIXEL2022: TSMC is trying to push designs away from 65nm and people start questioning the long-medium term availability of this technology.

The TSMC 28nm technology is the most performant planar mainstream solution that evolved through the years due to constant enhancements in the manufacturing process.

It supports a wide range of applications, including CPUs, GPUs, high-speed networking chips, smart phones, APs, tablets, home entertainment, consumer electronics, automotive and IoT.

It mainly uses High-k Metal Gate (HKMG) gate-last technology. Compared to the gate-first technology, the gate-last offering provides more advantages, including lower leakage current and better chip performance.



	Shrink technology: YES
	Core voltage: 0.9V
	I/O voltage: 1.8V
	Shallow Trench Isolation (STI)
	Wells: Retrograde twin well for low well
	sheet resistance and better latch-up
	behavior.
	Triple well, Deep N-Well in option
	Dual Gate Oxide
Technology characteristics	Vt options: ulvt, lvt, svt, hvt, uhvt, ehvt
	5V HVMOS
	HighRes resistors
	Temperature range: -40C to 125C
	# of metals: 5 to 10 Cu + ALRDL
	Interconnect dielectric: ELK
	Top metal: 8.5KA, 11.5KA, 35KA
	CMP on STI, contact, via and passivation
	MoM capacitor
	Passivation: dual layers



Options that need special attention	SRAM Cell Vt's: maximum of 4 VT types in one
Options that need special attention	design.
Wafer size	12 inch
Deliverables	100 dies, no wafer
Design tools	PDK: TSMC iPDK
Simulation tools	HSPICE, Eldo, Spectre
Verification tools DRC	Cadence, Siemens EDA, Synopsys
Verification tools LVS	Cadence, Siemens EDA, Synopsys
Parasitic extraction tools	Cadence, Siemens EDA, Synopsys
P&R tools	Cadence, Siemens EDA, Synopsys
	12-track / 9-track / 7-track core cell
	libraries, multi-vt's
Foundry IP	0.9V/1.8V hybrid staggered (fail-safe
	digital and regular analog) I/O library
	SRAM compilers by TSMC , ARM,
	Synopsys
MPW block size	6mm² (on silicon)
	Supported
Mini@sic characteristics	Min area: 1mm <sup>2</sup> (post-shrink)
	mini@sic Technology options



Other technical details

• Lower metal layers:  $0.45\Omega/\Box$ 

(UMC110: M1=0.17 Ω/□;M2= 0.13Ω/□)

• fT above 300 GHz



#### Recommended 28 nm mini@sic options

Metal Scheme	9M_5XIYIZIU UT-ALRDL
Flip-Chip/bumping	Not supported in the common flow. Please contact eptsmc@imec.be.
Allowed devices	<ul> <li>(1) ultra low Vt = {VTUL_N OR VTUL_P}</li> <li>(2) low Vt = {VTL_N OR VTL_P}</li> <li>(3) high Vt {VTH_N OR VTH_P}</li> <li>(4) ultra high Vt = {UHVT_N OR UHVT_P}</li> <li>Standard devices are by default allowed</li> <li>Contact <u>eptsmc@imec.be</u> if other Vt's are needed.</li> </ul>
SRAM/ ULL SRAM	Not supported in the common flow. Please contact <a href="mailto:eptsmc@imec.be">eptsmc@imec.be</a> .
AP thickness	28kA
Backlapping thickness	l I mils

Important note:

Always use the T-N28-CR-SP-029 (mmWave ULL) PDK with flavor RF HPC+ 0.9/1.8V.

Sub-dicing of multiple sub-chips is not possible.



# **Restrictive Design Rules**

- Starting from the 28 nm technological node, the design rules are becoming much more complex in terms of device usage, density requirements and physical design limits.
- Poly and metal density must be kept very uniform across the die in order to fabricate the minimum channel length devices in a reliable way.
- Beside limits on the minimum and maximum poly density, there are also rules for the maximum poly area per device finger: large area devices must be fragmented
- Gate orientation of all the devices must be uniform across the whole wafer, circuits rotation is strictly prohibited.
- Maximum transistor gate area, maximum transistor width W and length L:in 28 nm the maximum W and L for a single device finger are 3µm and 1µm, respectively.



# **Radiation Hardness**

- Enclosed-layout devices not possible
- Circuital approaches more challenging (and not always enough)
- Ultra-scaled technologies, and especially the 28 nm, results to be more radiation resistant than the others
  - radiation damage is proportional to gate oxide volume
  - gate dielectric has been replaced with high-k materials



## Accessibility through EP

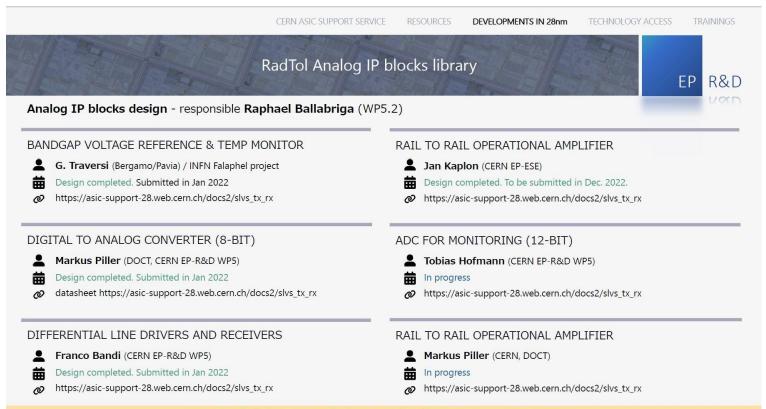
#### mini@sic:

- HPC: 1 run/year
- HPC+: 3 runs/year

#### MPW:

• HPC/HPC+: 12 runs/year





More details in the presentation by Franco Bandi: https://indico.cern.ch/event/1207114/



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#### CERN ASIC SUPPORT SERVICE **DEVELOPMENTS IN 28nm** RadTol Analog IP blocks library Fundamental IP blocks - responsible ASIC Support Service RADIATION TO FRANT FSD PROTECTIONS RADIATION TOLERANT CMOS IO PAD outsourced to SOFICS by the CERN ASIC Support Outsourced to SOFICS by the CERN ASIC Support Design completed. Submitted in Jan 2022 for radiation characterization. In progress. Radiation characterization will follow. m 龠 https://asic-support-28.web.cern.ch/docs2/slvs tx rx https://asic-support-28.web.cern.ch/docs2/slvs\_tx\_rx Q Q SRAM MEMORIES **EFUSES** Compilers purchased from the Foundry by the CERN ASIC Support IP block purchased from the Foundry by the CERN ASIC Support We can distribute precompiled memory upon request 曲 Radiation characterization will follow. Submitted in Jan 2022. Radiation characterization completed.

https://asic-support-28.web.cern.ch/docs2/slvs\_tx\_rx Q



• K. Kloukinas:

«A full maskset with all technology options and maximum metal stack (9 metals) is **1.2 million USD**». As a reference: 110nm UMC: 150,000 USD 65nm TSMC: 500,000 USD

MPW are on the contrary rather cheap, I don't have a number but I think ~40,000 for the minimum size. MiniAsics are possible.



- We should receive the NDA to sign vwery soon (today?)
- It should go much quicker than with 65nm: